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**PATENT APPLICATION**

**RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 2828**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Daniel KOPF et al.

Group Art Unit: 2828

Application No.: 10/006,396

Examiner: D. NGUYEN

Filed: December 10, 2001

Docket No.: 111399

For: HIGH POWER AND HIGH GAIN SATURATION DIODE PUMPED LASER MEANS  
AND DIODE ARRAY PUMPING DEVICE

**AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the August 25, 2005 final Office Action and in view of the November 22,  
2005 personal interview, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**